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**LIST OF PRIOR ART CITED BY APPLICANT**  
(Use several sheets if necessary)

APPLICANT  
Michael J. Daneman, Behrang Behin

FILING DATE  
11/13/2000

GROUP  
Not yet assigned

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE IF APPROPRIATE
RC	A	5 6 4 5 6 8 4	7/8/97	Keller	156	643.1	6/7/1995
	B	5 7 1 7 6 3 1	2/10/98	Carley et al.	365	174	6/25/1995
	C	5 9 0 8 7 1 9	6/1/99	Guckel et al.	430	5	9/11/1998
	D	5 9 7 1 3 5 5	10/26/99	Biegelsen et al.	251	129.06	11/27/1996
	E	5 9 4 9 5 7 1	9/7/99	Goossen et al.	359	291	7/30/1998
	F	5 9 4 3 1 5 5	8/24/99	Goossen	359	247	8/12/1998
	G	5 8 6 6 2 8 1	2/2/99	Guckel et al.	430	22	11/27/1996
	H	5 6 3 8 9 4 6	6/17/97	Zavracky	200	181	1/11/1996
	I	5 6 3 7 5 3 9	6/10/97	Hofmann et al.	438	20	1/16/1996
	J	5 3 2 7 0 3 3	7/5/94	Guckel et al.	310	40	12/30/1992
	K	5 2 0 6 9 8 3	5/4/93	Guckel et al.	29	598	5/24/1991
	L	5 0 4 3 0 4 3	8/27/91	Howe et al.	21	306	6/22/1990
	M	5 9 1 4 5 0 7	6/22/99	Polla et al.	257	254	10/30/1996
	N	6 0 2 5 9 5 1	2/15/00	Swart et al.	359	245	11/27/1996
	O	5 3 1 4 5 7 2	5/24/94	Core et al.	156	643	4/22/1992
	P	6 2 0 3 7 1 5	3/20/01	Kim et al.	216	24	1/19/1999
	Q	6 0 2 1 6 7 5	2/8/2000	Sefeldt et al.	73	777	2/28/1997
	R	5 5 7 6 2 5 0	11/19/1996	Diem et al.	437	228	12/27/1993
RC	S	5 7 8 0 8 8 5	7/14/1998	Diem et al.	257	254	8/15/1996

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
RC	T	1 0 3 3 6 0 1	6/9/2000	Europe	G02B	26/02		X
	U	2 3 2 1 7 8 0	8/5/1998	Great Britain	H01L	37/02		X
	V	0 6 0 5 3 0 0	7/6/1994	Europe	G01P	15/08		X
RC	W	0 9 4 2 4 6 2	9/15/1999	Europe	H01L	21/311		X
								X



OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
X		Yao et al., "Single Crystal Silicon Supported Thin Film Micro Mirrors for Optical Applications" Opt. Eng. 36(5) 1408-1413 (May 1997)
Y		Conant et al. "A Flat High Frequency Scanning Micromirror" Abstract Submitted to Hilton Head 2000.
Z		Storment et al. "Flexible Dry Release Process for Aluminum Electrostatic Actuators" Journal of Microelectromechanical System Vol. 3 No. 3 Sept 1994
AA		Mita et al., "An Out-of-Plane Polysilicon Actuator With a Smooth Vertical Mirror for Optical Fiber Switch Application"
AB		Marxer et al. "Vertical Mirrors Fabricated by Deep Reactive Ion Etching For Fiber-Optic Switching Applications" Journal of Microelectromechanical Systems, Vol. 6 No. 3, Sept 1997
AC		Fedder, G.K., "integrated microelectromechanical systems in conventional CMOS", Proceedings of 1997 IEEE International Symposium on Circuits and Systems. Circuits and Systems in the Information Age. ISCAS '97 (Cat. No. 97CH35987), pages 2821-2824, vol. 4
EXAMINER		DATE CONSIDERED
Robert Gilbert		10/21/02
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